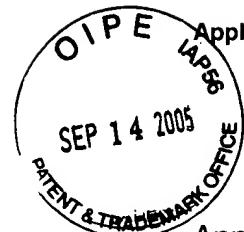


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DPM 2813
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/212,726
Filing Date December 15, 1998
Inventor..... Klaus F. Schuegraf
Assignee..... Micron Technology, Inc.
Group Art Unit..... 2813
Examiner Kielin, Erik J.
Attorney's Docket No. MI22-1098
Title: Semiconductor Processing Methods of Chemical Vapor Depositing SiO₂ on a Substrate

RESPONSE TO JUNE 14, 2005 OFFICE ACTION

To: Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)
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AMENDMENTS

Introductory Comments

In reply to the office action dated June 14, 2005, applicant amends and remarks as follows.